TIGHTEN CONTROL OF YOUR TEMPERATURE-CRITICAL PROCESS WITH ACTIVE EMISSIVITY COMPENSATION

Material surface properties often change during the manufacturing process as a result of oxidation or through the introduction of coatings. This change affects the emissivity of the material being measured, which is a critical parameter for accurate pyrometer temperature measurement. Compared to pyrometers that use a fixed emissivity value, those with real-time emissivity compensation enable much better accuracy and repeatability by continuously measuring and correcting for changes in substrate emissivity.

With active emissivity compensation, temperature measurement accuracy remains constant despite substrate emissivity changes.

Without active emissivity compensation, false temperature measurements may be introduced into your temperature-critical process, which degrades temperature control accuracy and product quality.

With real-time emissivity measurement and compensation, Onyx™-MCE emissometers achieve superior accuracy and repeatability.